



Radiation Effects in Low-Gain Avalanche Detectors LGAD

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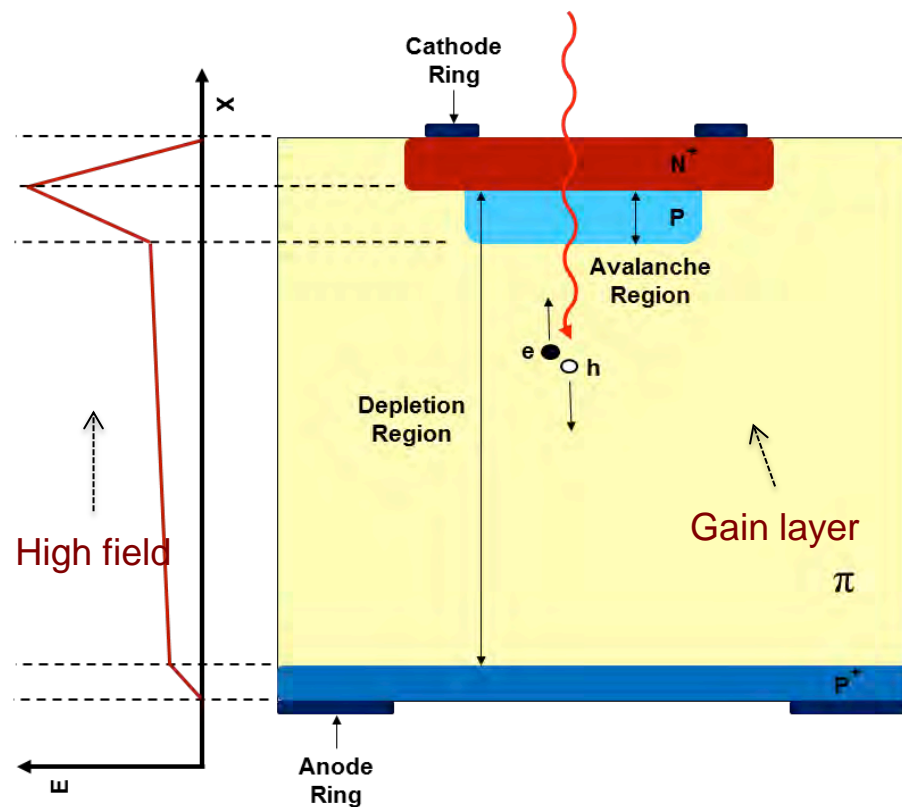
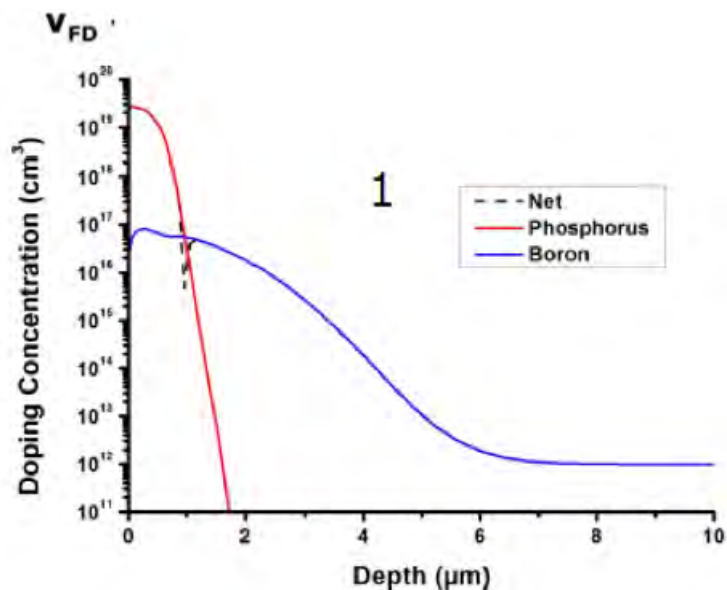
- LGAD
- Radiation Effects in Silicon
- Radiation Effects in LGAD
- Mitigation Program

Low Gain Avalanche Detectors (LGADs)

The LGAD sensors, as proposed and manufactured by CNM & FBK

High field obtained by adding an extra doping layer

$E \sim 300$ kV/cm, closed to breakdown voltage



Gain in Silicon detectors

Gain in silicon detectors is commonly achieved in several types of sensors. It's based on the avalanche mechanism that starts in high electric fields: $E \sim 300 \text{ kV/cm}$

Charge multiplication $N(l) = N_0 \cdot e^{\alpha l}$

Gain: $G = e^{\alpha l}$

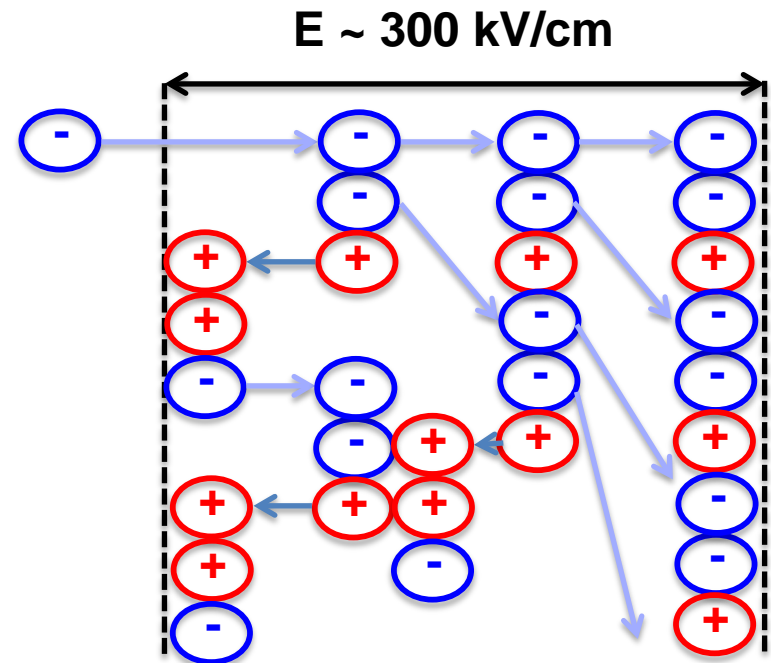
$$\alpha_{e,h}(E) = \alpha_{e,h}(\infty) \cdot \exp\left(-\frac{b_{e,h}}{|E|}\right)$$

α = strong E dependance
 $\alpha \sim 0.7 \text{ pair}/\mu\text{m}$ for electrons,
 $\alpha \sim 0.1$ for holes

Concurrent multiplication of electrons and holes generate very high gain

Silicon devices with gain:

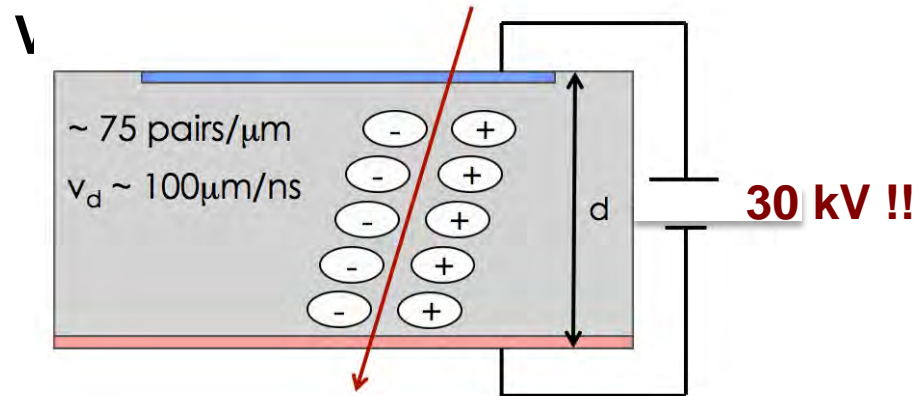
- APD: gain 50-500
- SiPM: gain $\sim 10^4$



How can we achieve $E \sim 300\text{kV/cm}$?

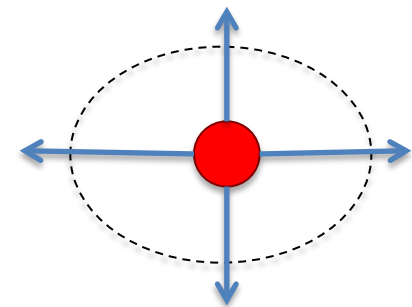
- 1) Use external bias: assuming a 300 micron silicon detector, we need

Not possible



- 2) Use Gauss Theorem:

$$\sum q = 2\pi r * E$$



$$E = 300 \text{ kV/cm} \rightarrow q \sim 10^{16} / \text{cm}^3$$

Need to have $10^{16}/\text{cm}^3$ charges !!

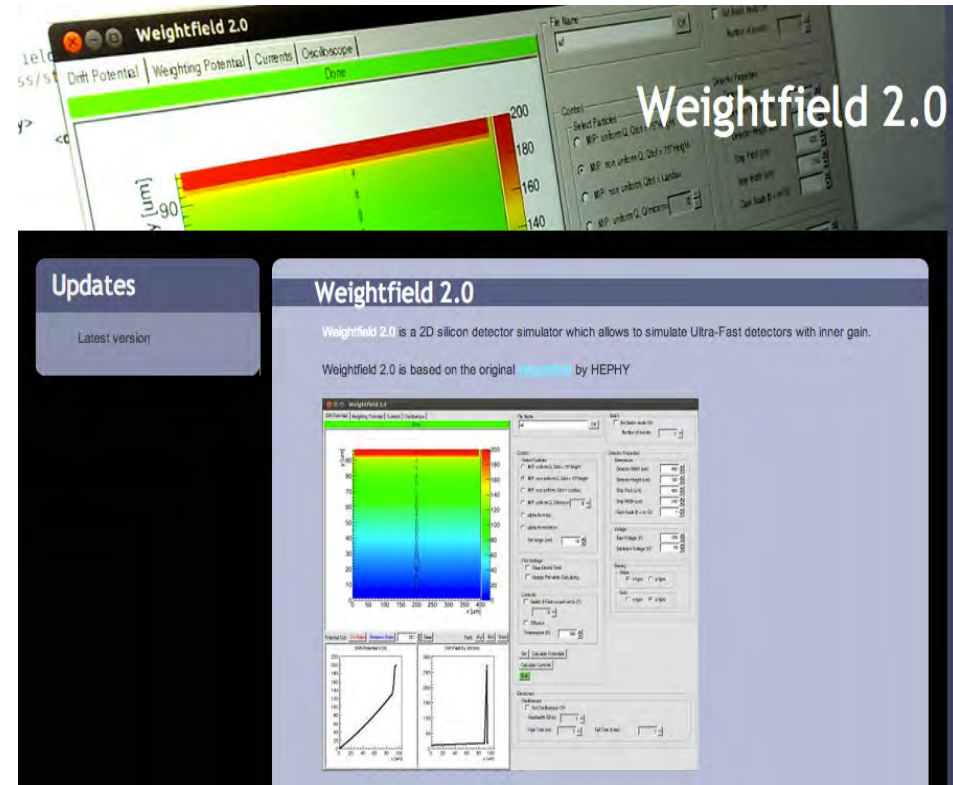
WeightField2: the Silicon Detector Simulator

Nicolo Cartiglia developed a full sensor simulation to optimize the sensor design

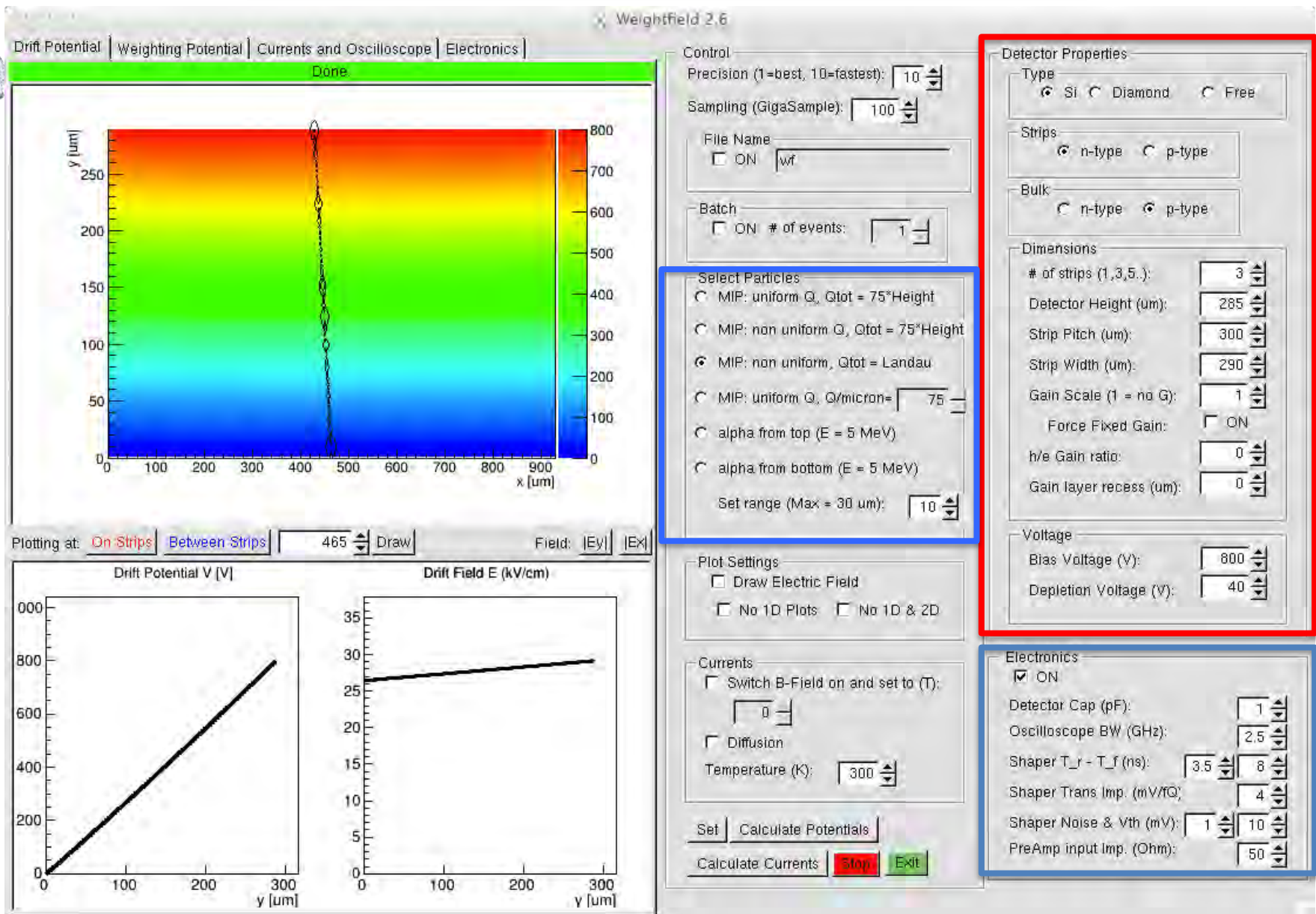
WeightField2, F. Cenna, N. Cartiglia 9th Trento workshop, Genova 2014

Available at <http://personalpages.to.infn.it/~cartigli/weightfield2>

It includes many “bells & whistles” required for the detailed description of the signals, i.e. charge generation, drift and collection. It allows to separate the properties of the current source from the amplifier shaping. Includes radiation damage. (Perfect to teach and learn about silicon sensors)

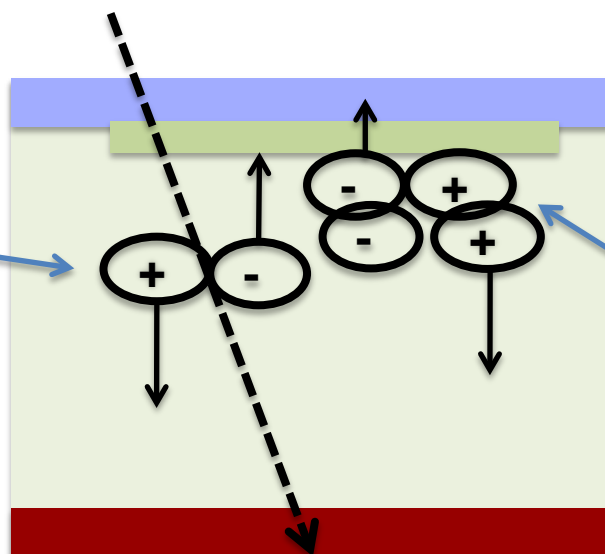


WeightField2: the Silicon Detector Simulator



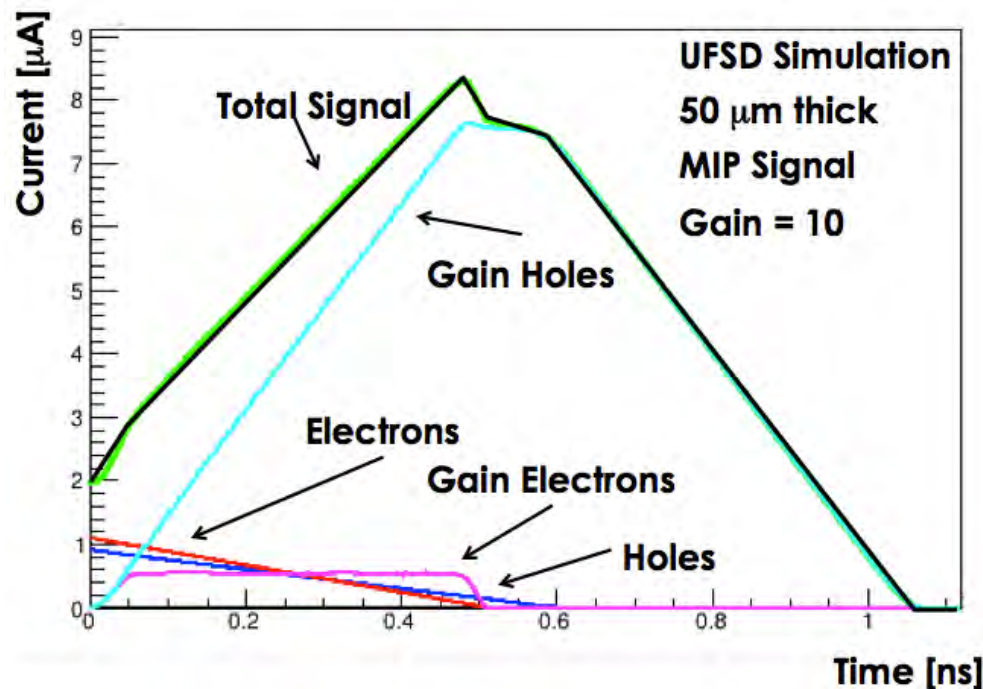
How gain shapes the signal

Initial electron, holes



Gain electron: absorbed immediately

Gain holes: long drift home



Electrons multiply and produce additional electrons and holes.

- **Gain electrons have almost no effect**
- **Gain holes dominate the signal**

➔ **No hole multiplication**



No-gain Silicon Pads: Current from 10 MiPs

Total current = electron current + hole current

Drift time difference electrons-holes clearly visible

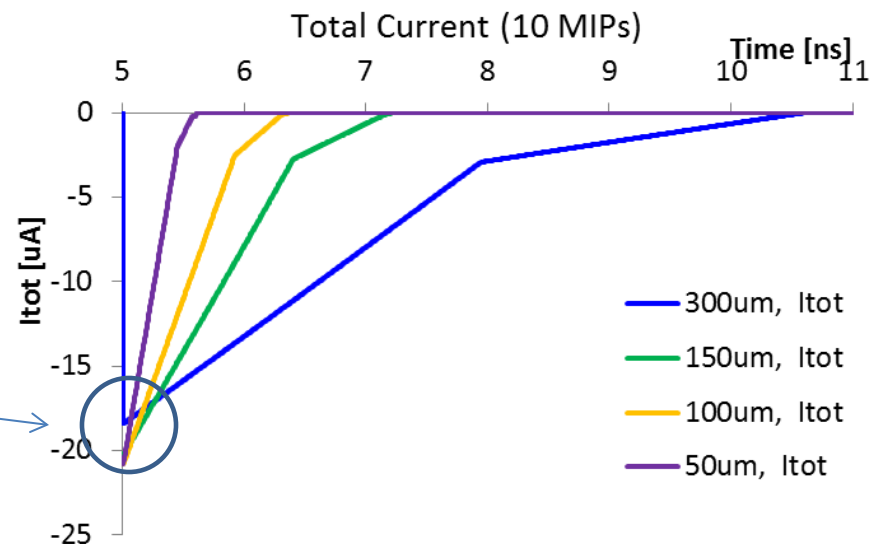
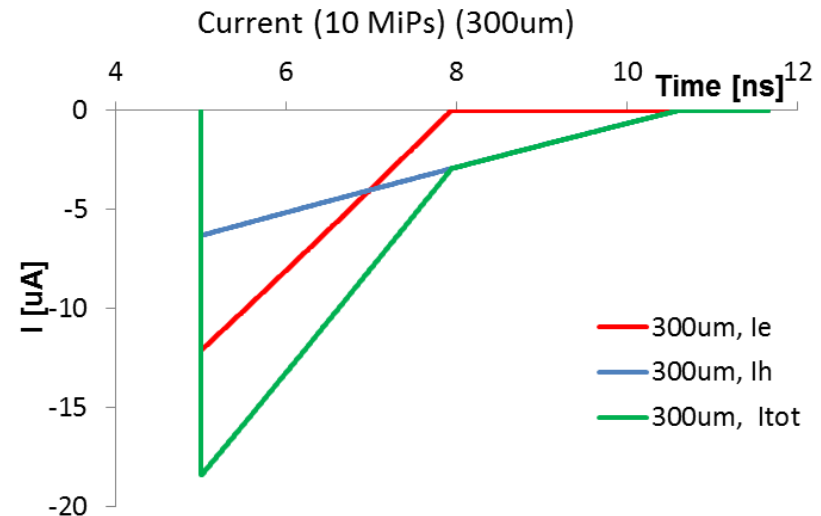
Most importantly:

The current peaks at $t=0$ where we want to make the time measurement

The current signal of sensors with different thickness' show that the height of peak at $t=0$ is independent of the detector thickness!

Thick detectors contribute to the tail.

The 300 μm sensor is not sufficiently over-depleted to reach saturation velocity, in contrast to the thinner ones.

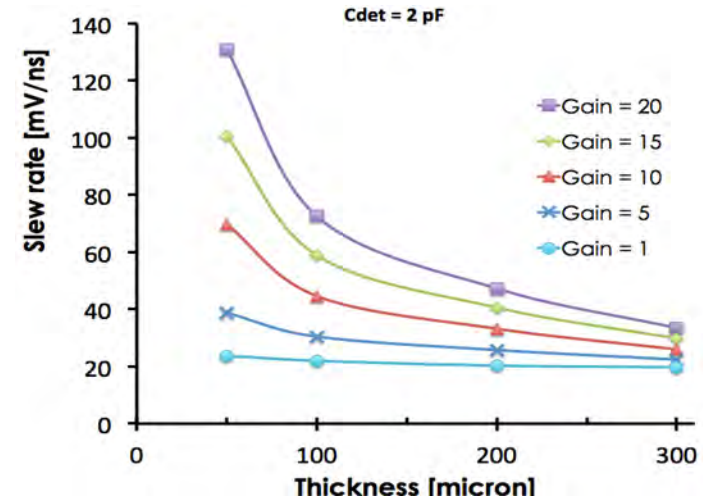


LGAD Timing Resolution

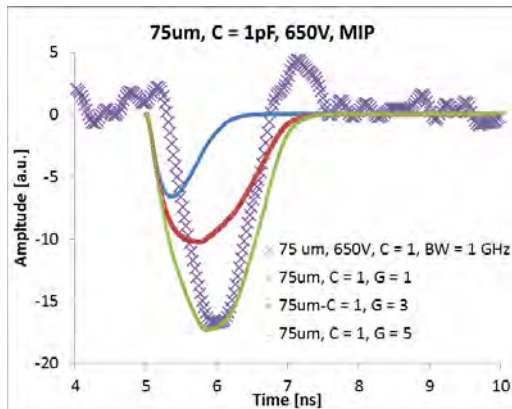
The timing resolution in silicon sensors can be expressed as the sum of four terms
time walk σ_{TW} , time jitter σ_J , Landau fluctuations σ_L and TDC binning σ_{TDC} :

$$\sigma_t^2 = \sigma_{TW}^2 + \sigma_J^2 + \sigma_L^2 + \sigma_{TDC}^2$$

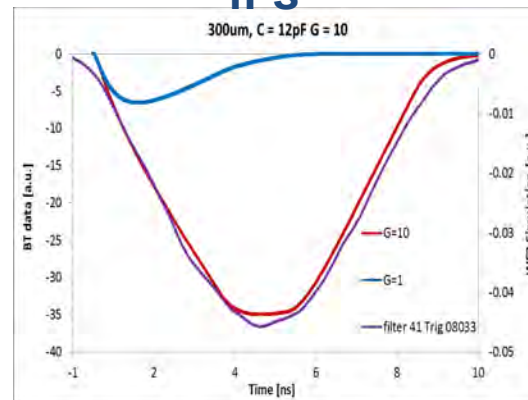
The first two terms are inversely
proportional to the slope dV/dt
-> need fast (i.e. thin sensors)
and large pulses (i.e. gain) .



75 μm LGAD, β 's



300 μm LGAD, 120 GeV π 's



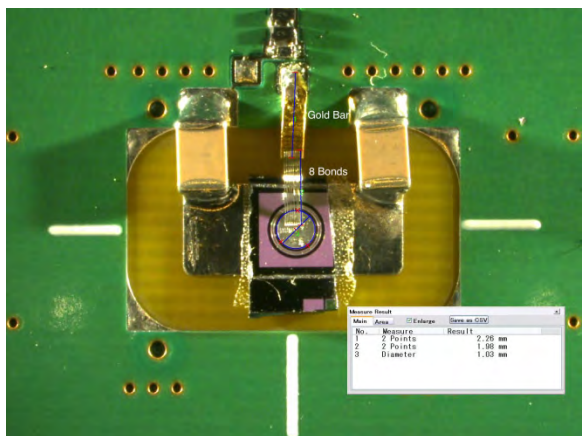
WF2 simulations
of 75 and 300 μm LGAD
reproduce the
observed pulse shapes

^{90}Sr β Telescope (A. Zatserklyaniy, Z. Galloway)

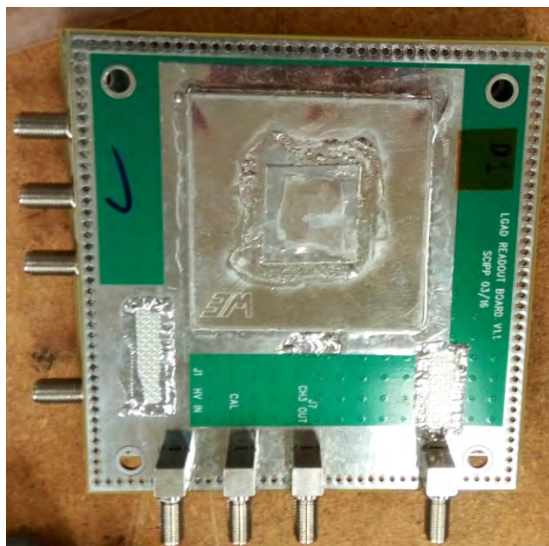
Stack of LGAD planes and the trigger plane



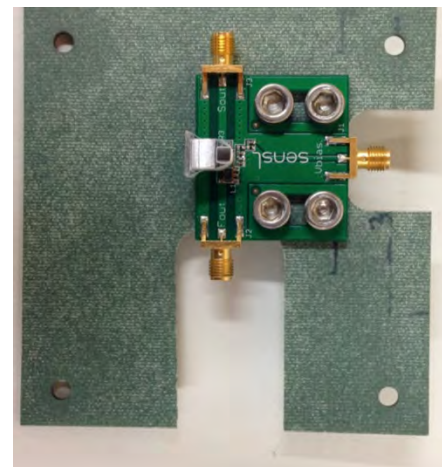
Reduced Inductance



Self-shielded LGAD



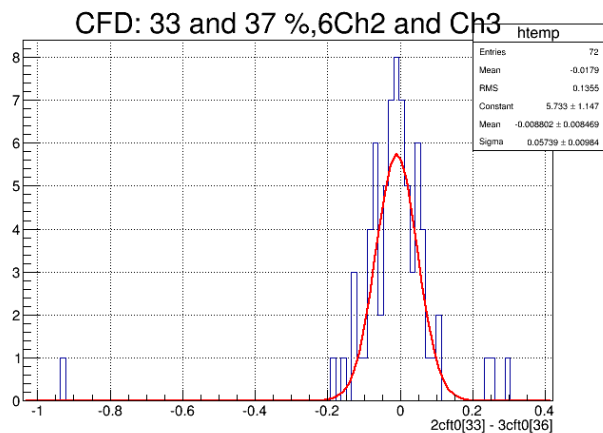
Quartz-SiPM Trigger



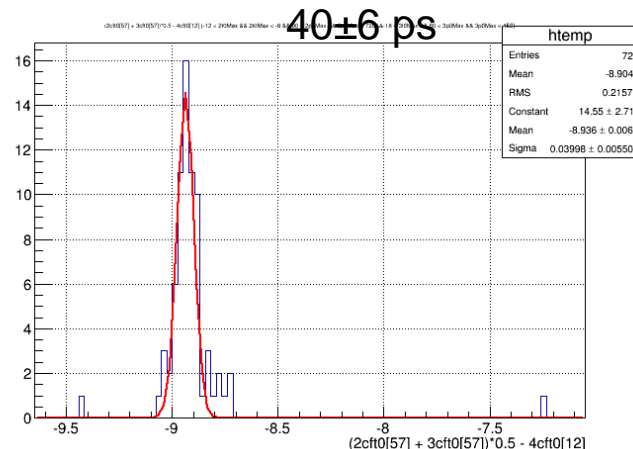
β Coincidence Data of 2 Thin LGAD

Plot time differences between:

1. between 2 LGADs average:
 $57 \pm 9 \text{ ps}$



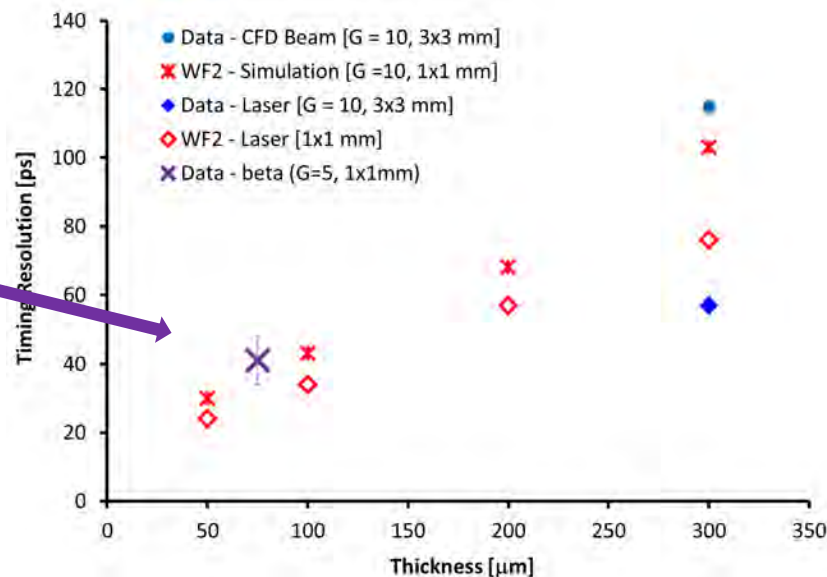
2. between average of 2 LGADs and trigger:
 $40 \pm 6 \text{ ps}$



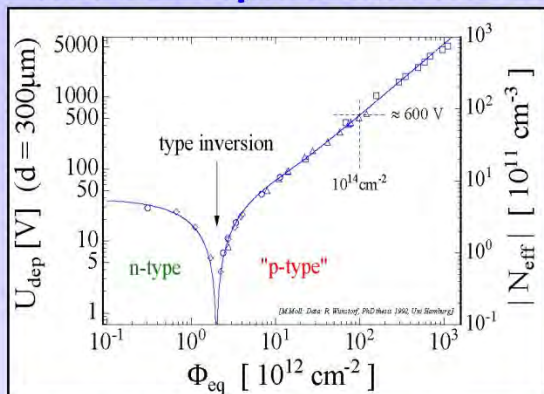
Timing Resolution (preliminary)
using Scope (sampling 20GS/s = 50ps) :
LGAD (75 μ , G=5) , $\sigma_{\text{TIME}} = 41 \pm 7 \text{ ps}$

Quartz&SiPM Trigger: $\sigma_{\text{TIME}} = 28 \text{ ps}$

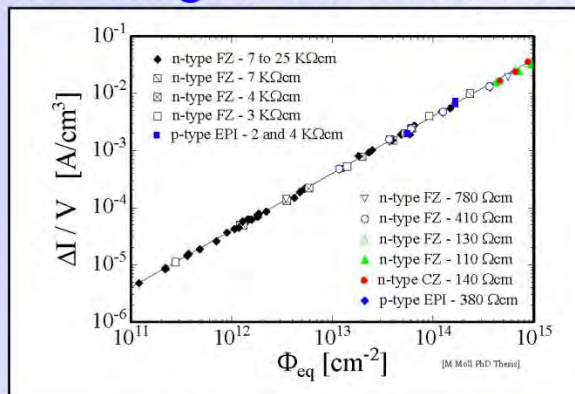
(Beam Test is being analyzed)



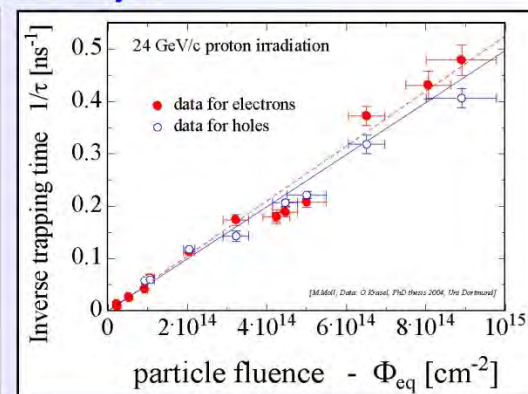
- Macroscopic bulk effects (annealing effects not shown here!) :



Depletion Voltage (N_{eff})

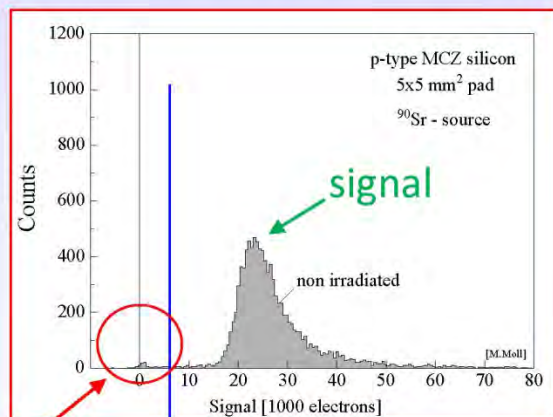


Leakage Current



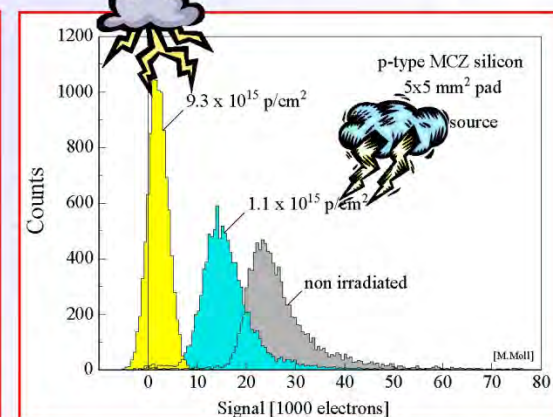
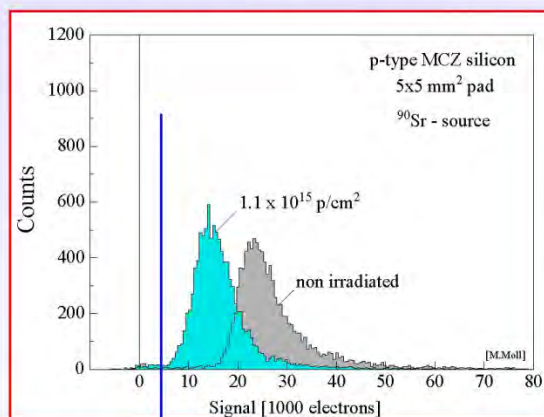
Charge Trapping

- Signal to Noise ratio is quantity to watch (material + geometry + electronics)



noise

Cut (threshold)





Aim of defect studies:

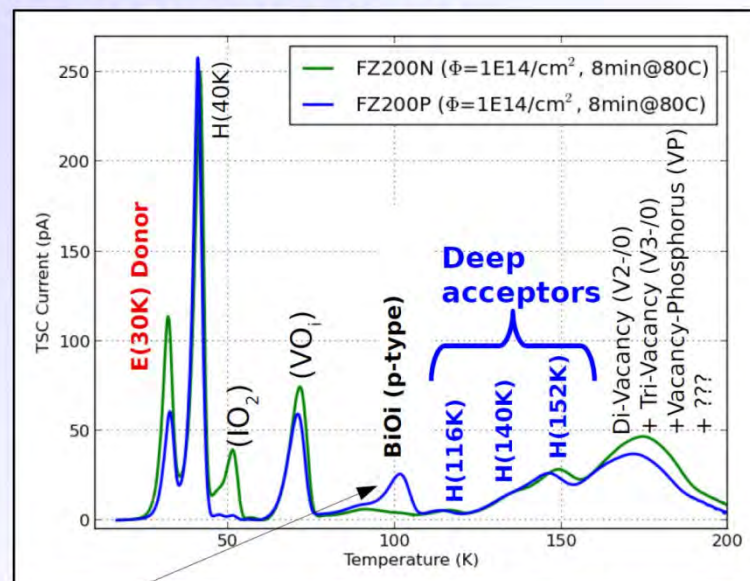
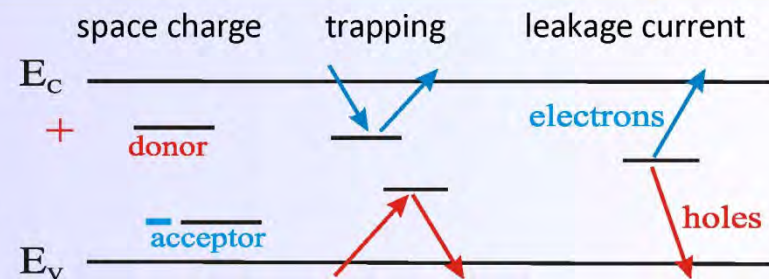
- Identify defects responsible for Trapping, Leakage Current, Change of N_{eff} , Change of E-Field
- Understand if this knowledge can be used to mitigate radiation damage (e.g. defect engineering)
- Deliver input for device simulations to predict detector performance under various conditions

Method: Defect Analysis performed with various tools inside RD50:

- C-DLTS** (Capacitance Deep Level Transient Spectroscopy)
- TSC** (Thermally Stimulated Currents)
- PITS** (Photo Induced Transient Spectroscopy)
- FTIR** (Fourier Transform Infrared Spectroscopy)
- EPR** (Electron Paramagnetic Resonance)
- TCT** (Transient Current Technique)
- CV/IV** (Capacitance/Current-Voltage Measurement)
- PC, RL, I-DLTS, TEM, ... and simulation*

- RD50: several hundred samples irradiated with protons, neutrons, electrons and ^{60}Co - γ

... significant progress on identifying defects responsible for sensor degradation over recent years!



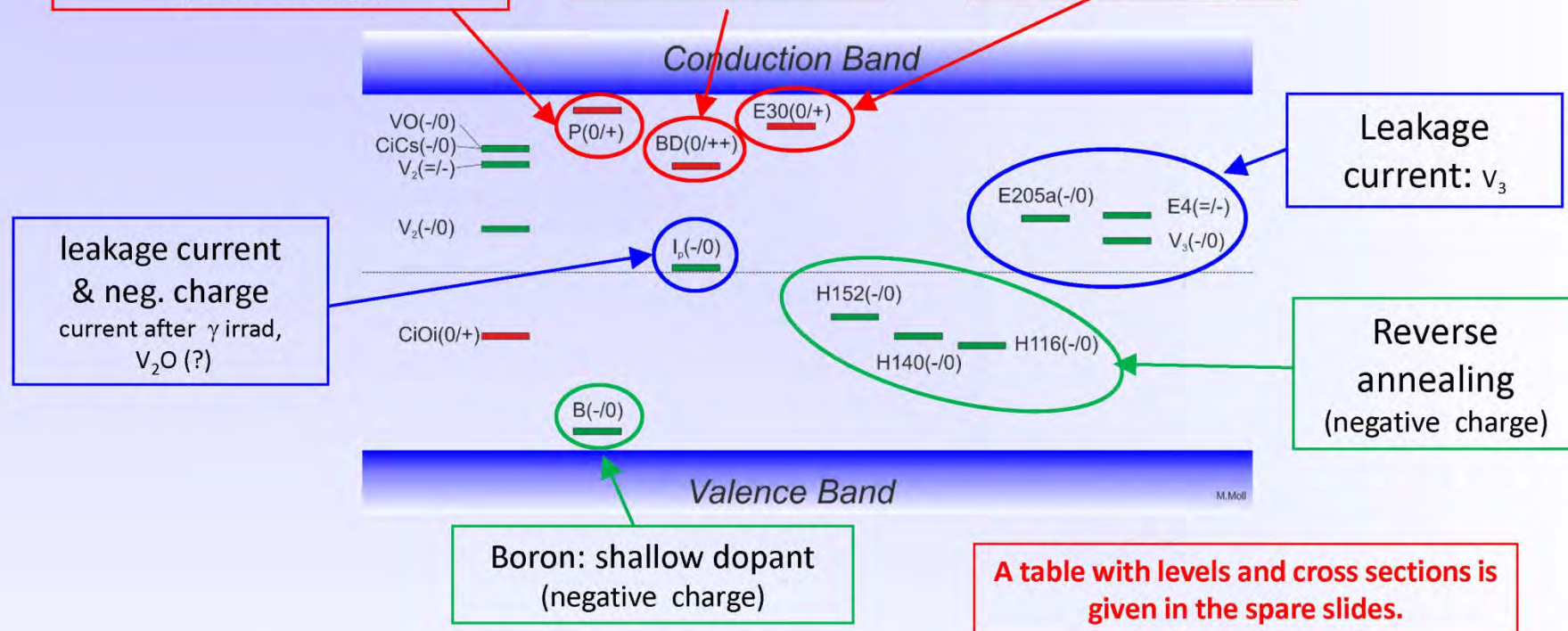
Example: TSC measurement on defects produced by 23 MeV protons

Some identified defects

Phosphorus: shallow dopant
(positive charge)

positive charge
(higher introduction after
proton than after neutron
irradiation, oxygen dependent)

positive charge
(higher introduction after
proton irradiation than after
neutron irradiation)



- **Trapping: Indications that E205a and H152K are important** (further work needed)
- Converging on consistent set of defects observed after p, π , n, γ and e irradiation.
- Defect introduction rates are depending on particle type and particle energy and (for some) on material!

Details: See spare slides!

M.Moll, AIDA-2020: Workshop on calorimetry with silicon , 13-17 June 2016 -8-

<https://indico.cern.ch/event/468478/contributions/2135148/attachments/1290271/1921271/1600613-RD50-AIDA2020.pdf>



Radiation Hardness of LGAD

The collected charge of LGAD detectors decreases with irradiation due to:

- a. Increase of depletion voltage (same as in no-gain silicon sensors -> go thin)
- b. Trapping of the drifting charges (same as in no-gain silicon sensors -> go thin)
- c. Trapping of holes modifying the detector bulk (more than in no-gain silicon sensors -> go thin)
- d. Removal of effective acceptors in the multiplication region

Point d. is slowly understood better and a few avenues of mitigation are being pursued by RD50.

Level of a few 10^{15} neq are foreseen (e.g. HSTD in ATLAS).

Mitigation:

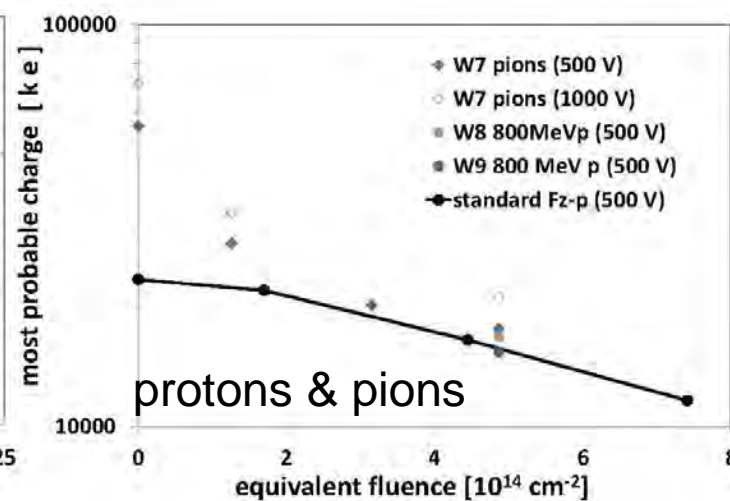
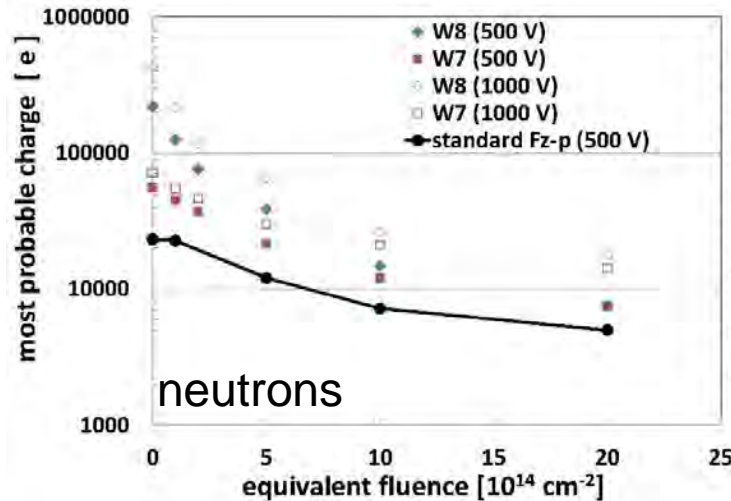
Replacing Boron with Gallium as dopant:

Carbon enriched Silicon wafers:

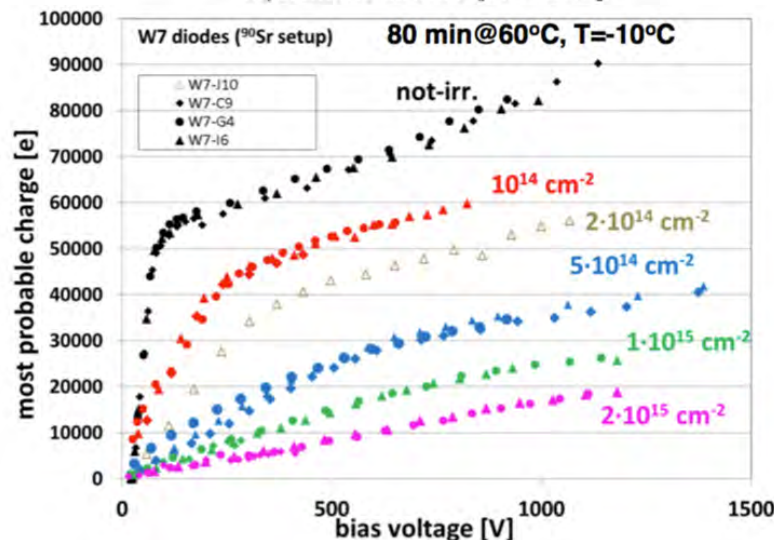
Balance gain from multiplication layer and bulk biasing

Radiation Damage in UFSD: Change in Gain

Measurement of collected charge (CCE) in 300 μm LGAD:
Gain = CCE(LGAD) / CCE(PiN)



G. Kramberger et al, 2015 JINST 10 P07006)



After $2 \times 10^{15} \text{ neq/cm}^2$ gain > 3.6

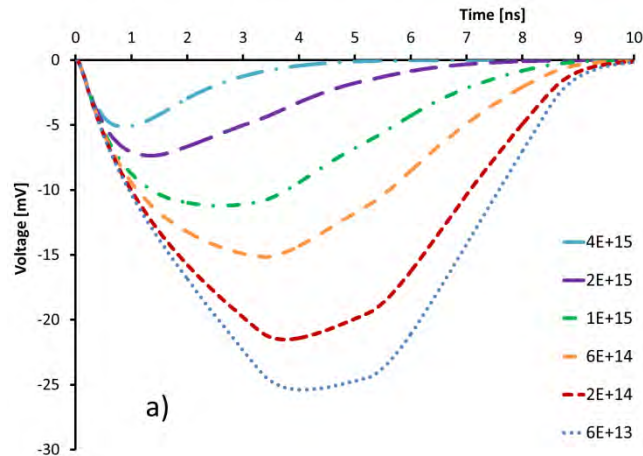
Leveling-off of gain degradation at higher fluences:
Competition between initial acceptor removal and gradual acceptor creation.



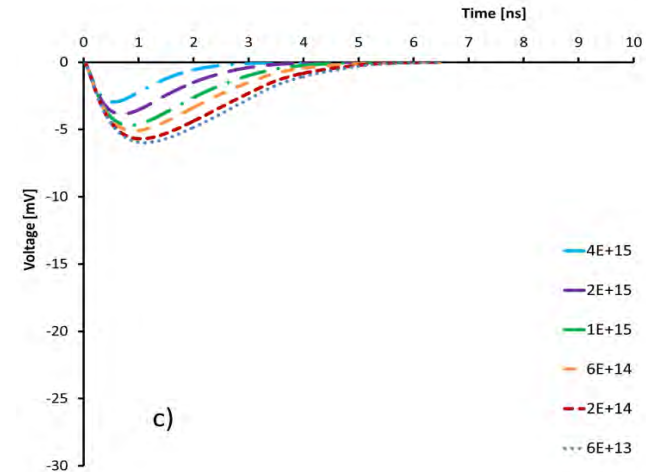
Radiation Damage in UFSD: Trapping only

Pulse shapes in LGAD vs. Fluence [neq/cm²]

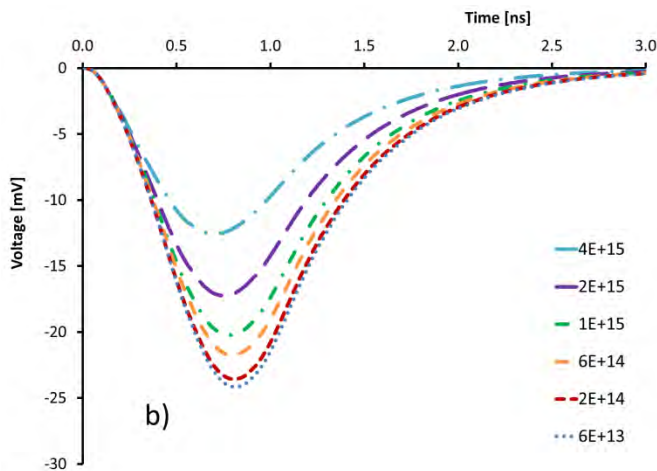
LGAD 300μm, Gain = 10



PiN 300μm, Gain = 1



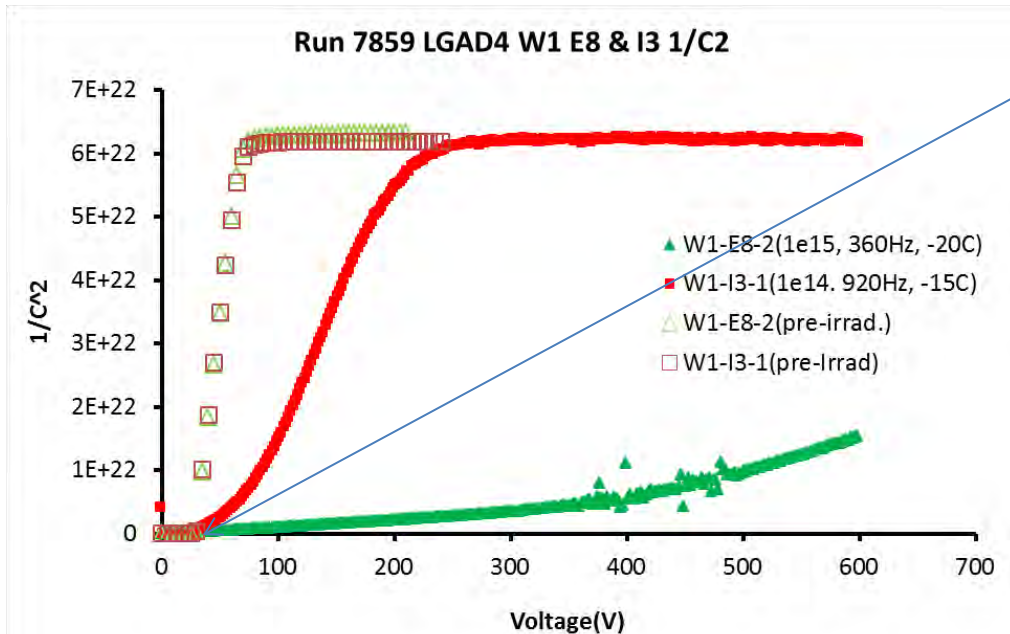
50μm, Gain = 10



Trapping mainly effects the late holes, but not the fast front edge which is important for timing..



C-V with 300 μm FZ LGAD (W1 Run 7859)



Pre-rad

“Foot” of 30V: gain ~ 5
Depletion Voltage: 75V

Post-rad

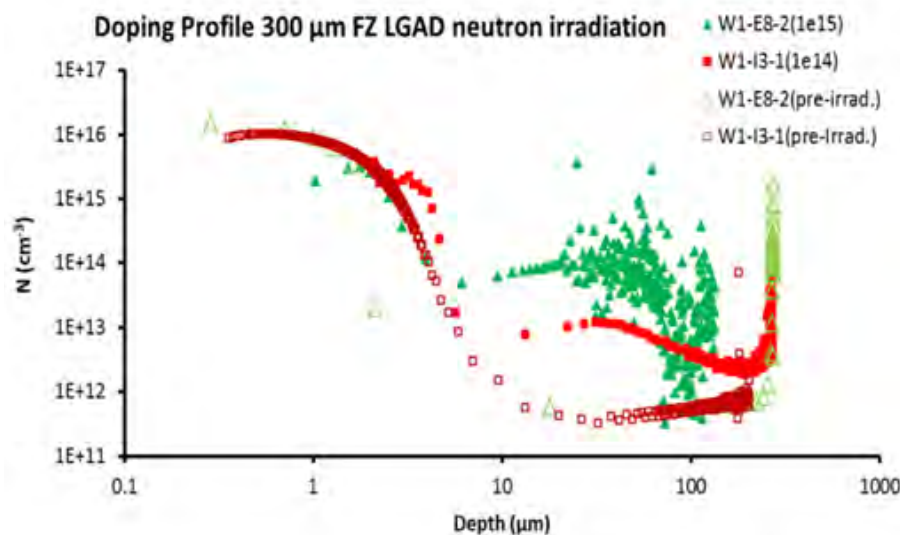
n fluence 10^{14} neq/cm 2 :

Foot of ~ 30 V
Depletion Voltage: 230V

n fluence 10^{15} neq/cm 2 :

Foot of ?V

Depletion Voltage: > 1000 V as expected

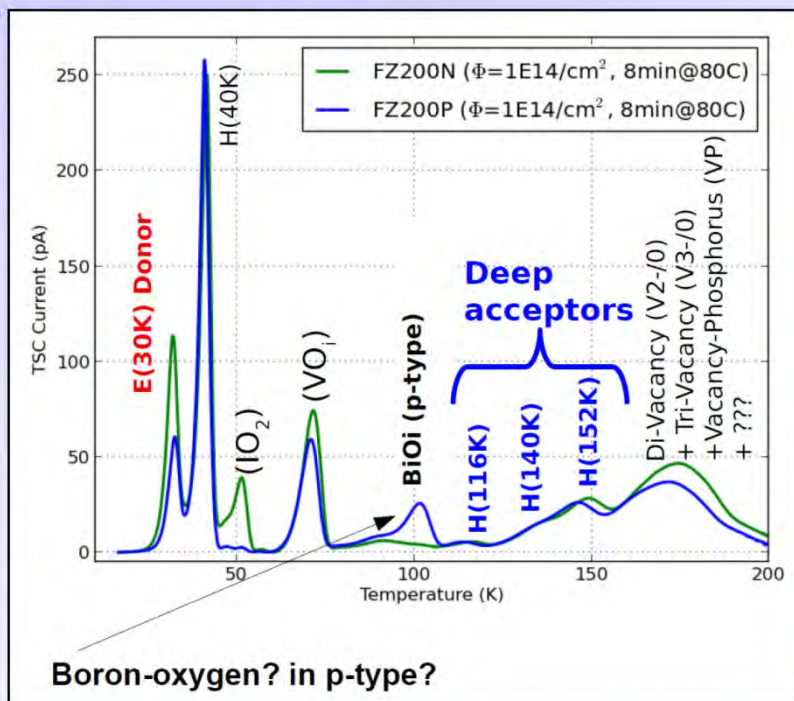


Measured doping profile extracted from C-V data on 300 μm LGAD for 0, 1e14 and 1e15 neq/cm 2

Bulk increases,
multiplication decreases

• Microscopic study of defects

- TSC (Thermally Stimulated Current) comparing n- and p-type sensors

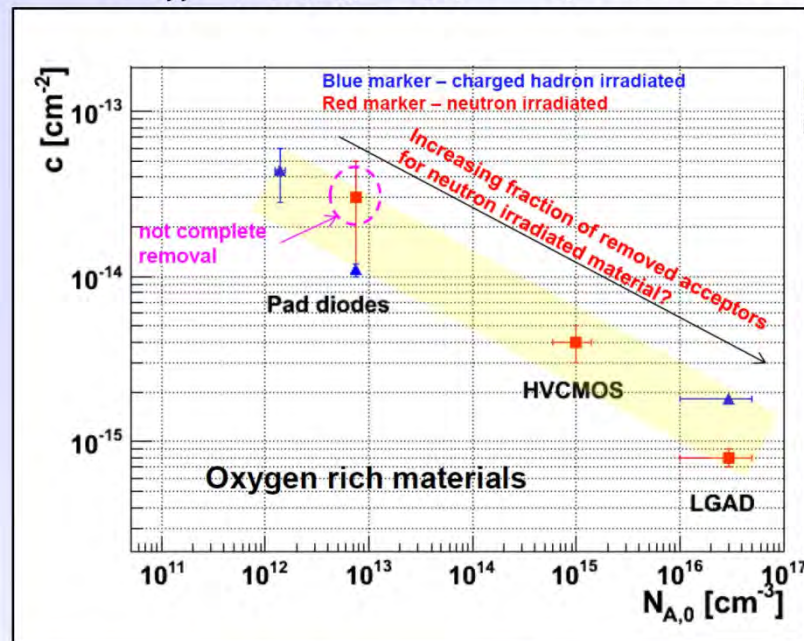


- Reminder: Deep acceptors (H(116K)..) and shallow donors (E30K) alter space charge
- Some defect only seen in p-type (Boron containing) material; indication for “Boron removal” by defect kinetics (e.g. B_i → B_iO_i)

• Macroscopic observation (Neff)

- p-type sensors of different resistivity show acceptor removal:

$$\Delta N_{eff} = |N_{Boron}| \cdot \exp(-c \cdot \Phi) + \dots \text{ [simplified]}$$

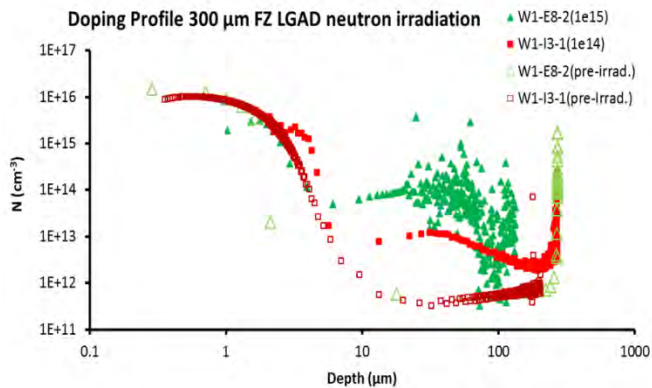


- So-called “acceptor removal” responsible for:
 - Gain degradation in sensors with intrinsic gain
 - Good performance of low resistivity CMOS sensors after high irradiation.
- Why not studied more intensively before?
 - Focus was on high resistivity and on n-type!



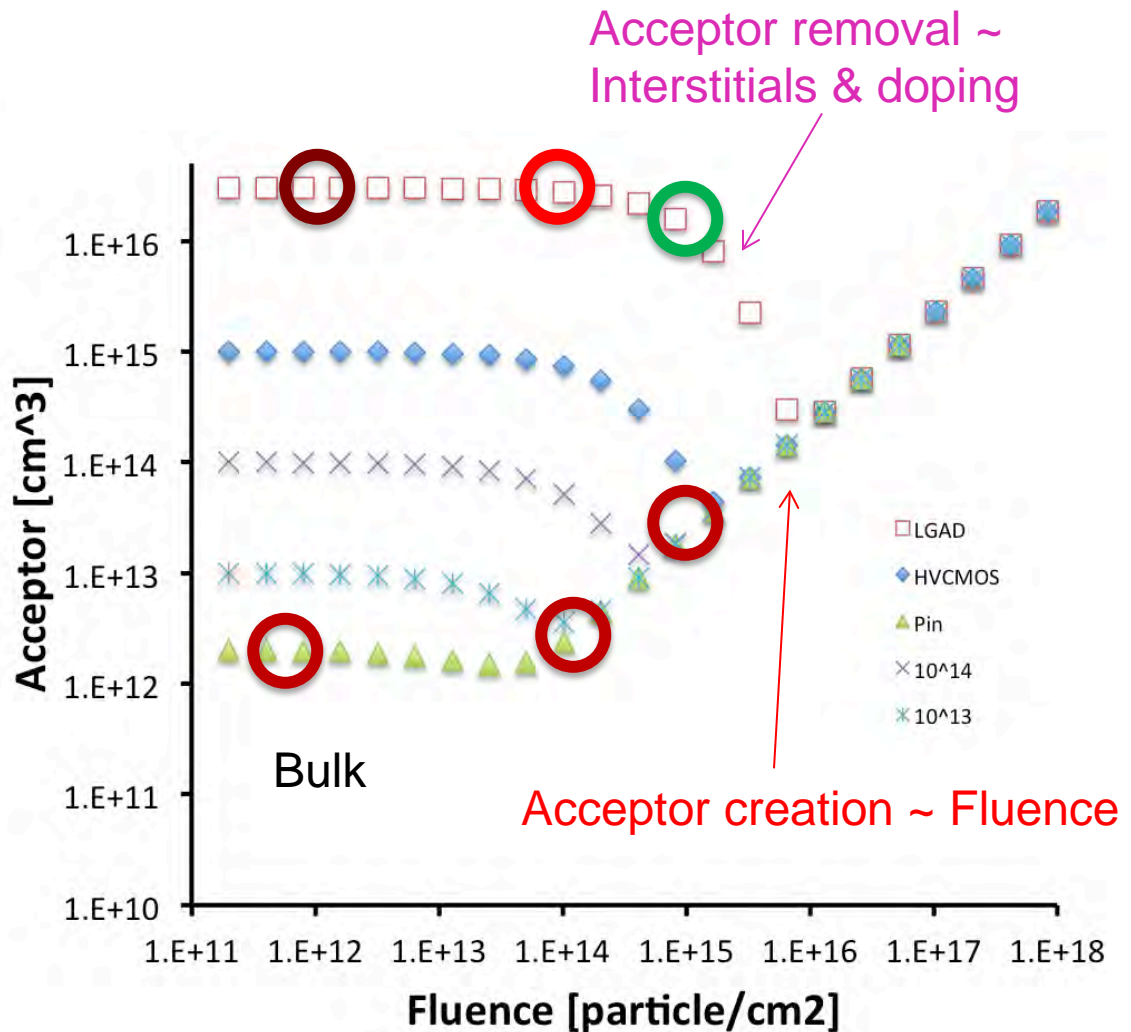
WF2 Model: FZ Bulk & gain good agreement

Hartmut F.-W. Sadrozinski, Radiation Effects in LGADs, 6/16/16



WF2 Model (**preliminary**)
based on
Gregor Kramberger's data on
300 μm LGAD, being revisited
with thin sensors.

FZ p gain-layer and bulk
follow quite closely
the prediction.





Improving Radiation Hardness of LGAD I

Replacing Boron with Gallium as dopant:

Ga or Al form complexes with radiation-induced defects (“interstitials”), which may have less impact on device performance, when compared to the boron related defect (Bi-Oi) complex. Using Ga as dopant in Si instead of B can reduce the acceptor removal effect.

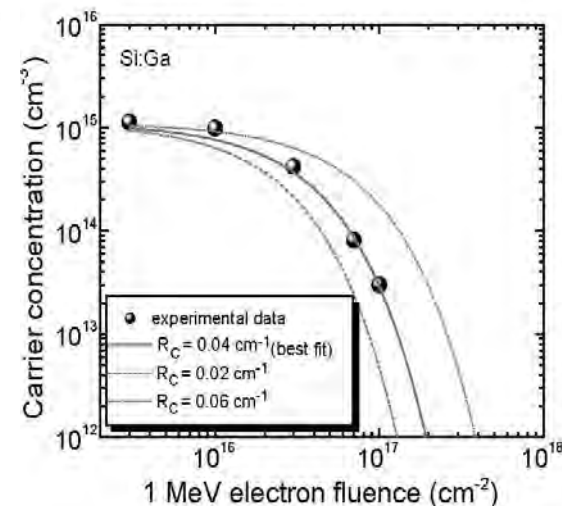
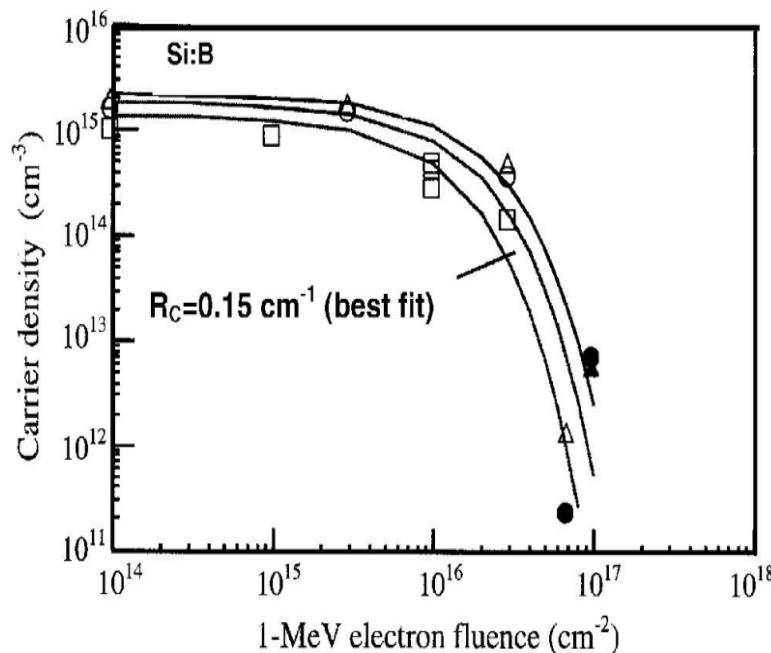
In fabrication at CNM

A. Khan et al.,
Solar Energy Materials & Solar Cells
75 (2003) 271–276

Carrier density removal @ 10^{17} :

Boron: $2e^{15} \rightarrow 1e^{12}$

Gallium: $1e^{15} \rightarrow 3e^{13}$



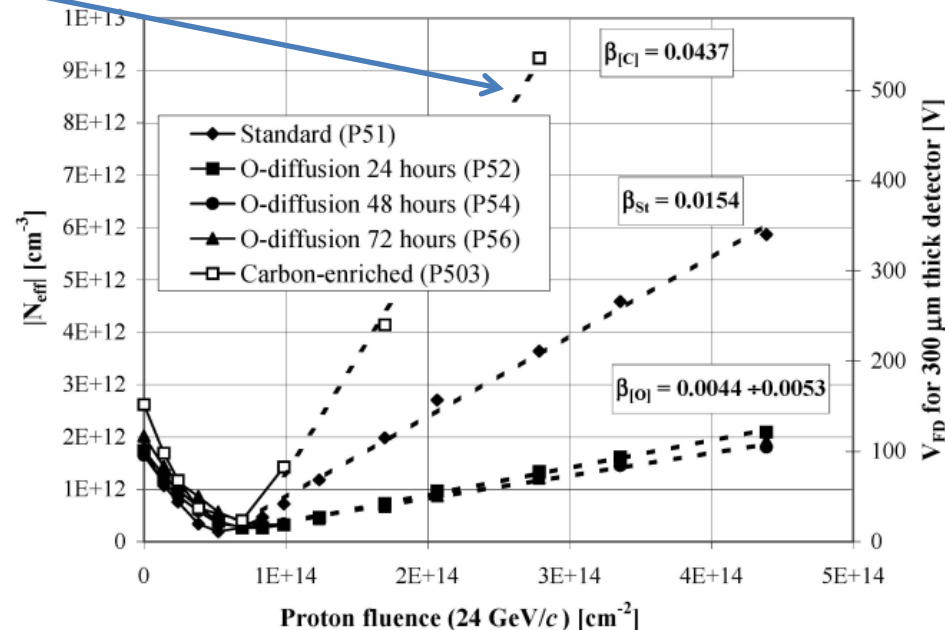
Improving Radiation Hardness of LGAD II

.Carbon enriched Silicon wafers:

RD48 collaboration observed that a high carbon concentration can reduce the formation of inactive Bi-Oi defects, as a result of the formation of more energetically favorable carbon-oxygen (C-O) complexes. Diffusing or implanting Carbon in the multiplication layer would suppress the acceptor removal during irradiation. *Two fabrication runs* are already in progress at CNM Barcelona in the framework of the RD50 collaboration.

Rose Collaboration, *NIMA 466 (2001) 308–326*

Carbon-enriched silicon retains more than twice the number of acceptors than FZ.



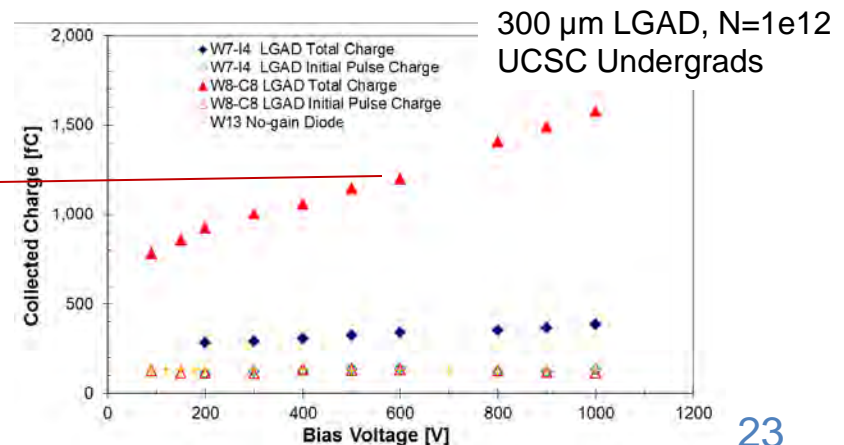
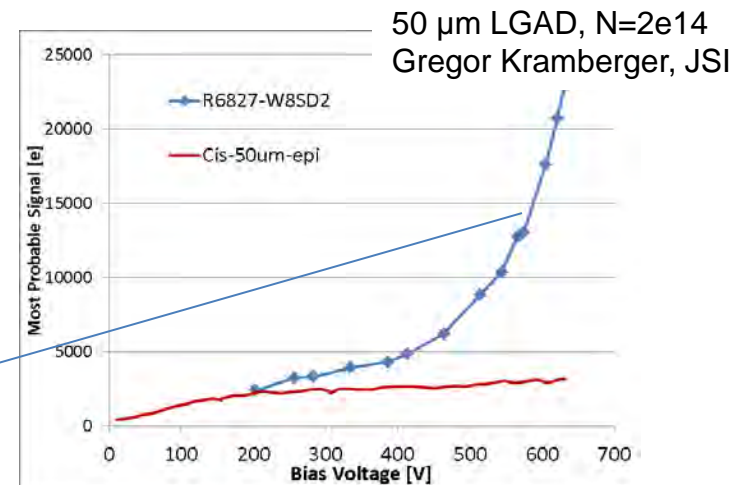
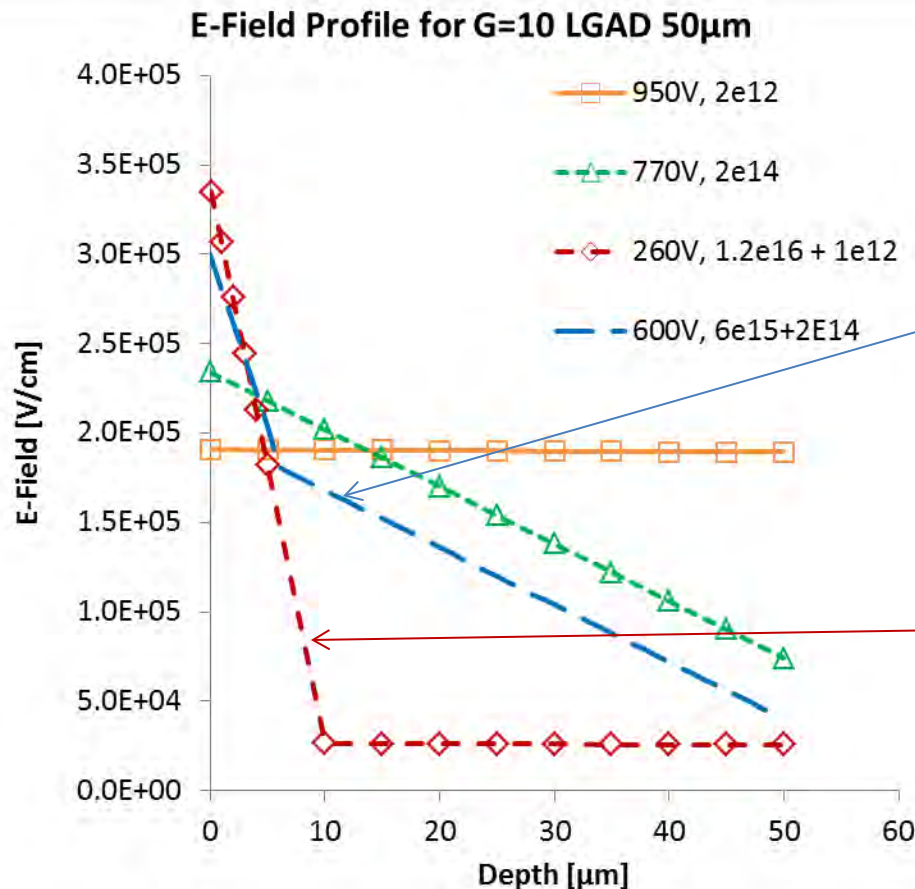


E-field in LGAD: bulk and “gain” field

LGAD's are characterized by the highly-doped thin p-layer which supplies the large field to satisfy the condition for charge multiplication.

The E-field needed for charge multiplication can be supplied by the bulk (high voltage operation needed!) or a combination of bulk and multiplication layer.

Bias dependence of the gain depends on the relative contribution of the two.





Mitigating Radiation Effects in LGAD III

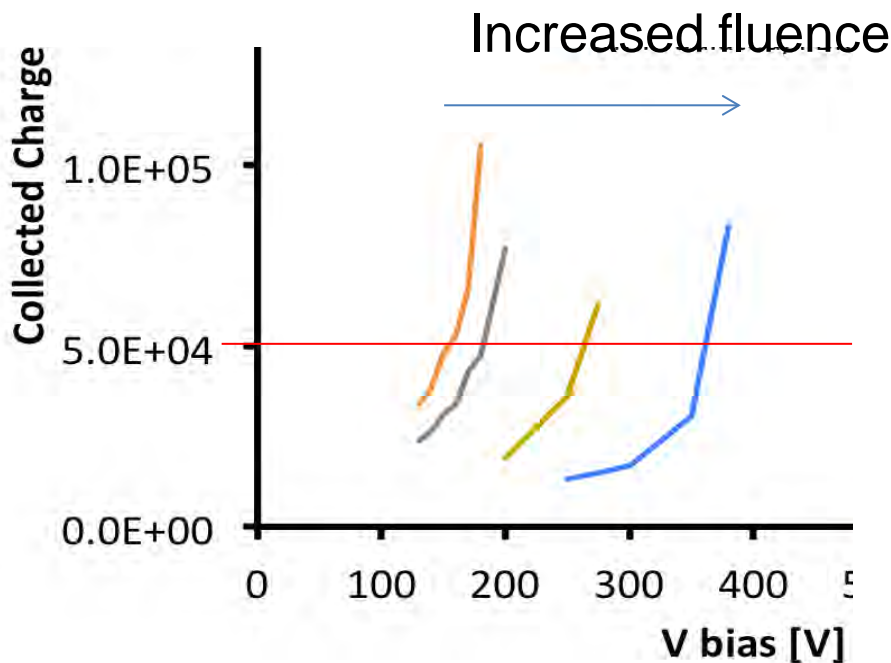
Balance gain from multiplication layer and bulk biasing

Start with high concentration of multiplication layer and low bias and increase bias when acceptor removal changes gain layer effectiveness.

This will keep the number of collected charges constant even when trapping dominates (in contrast to no-gain sensors).

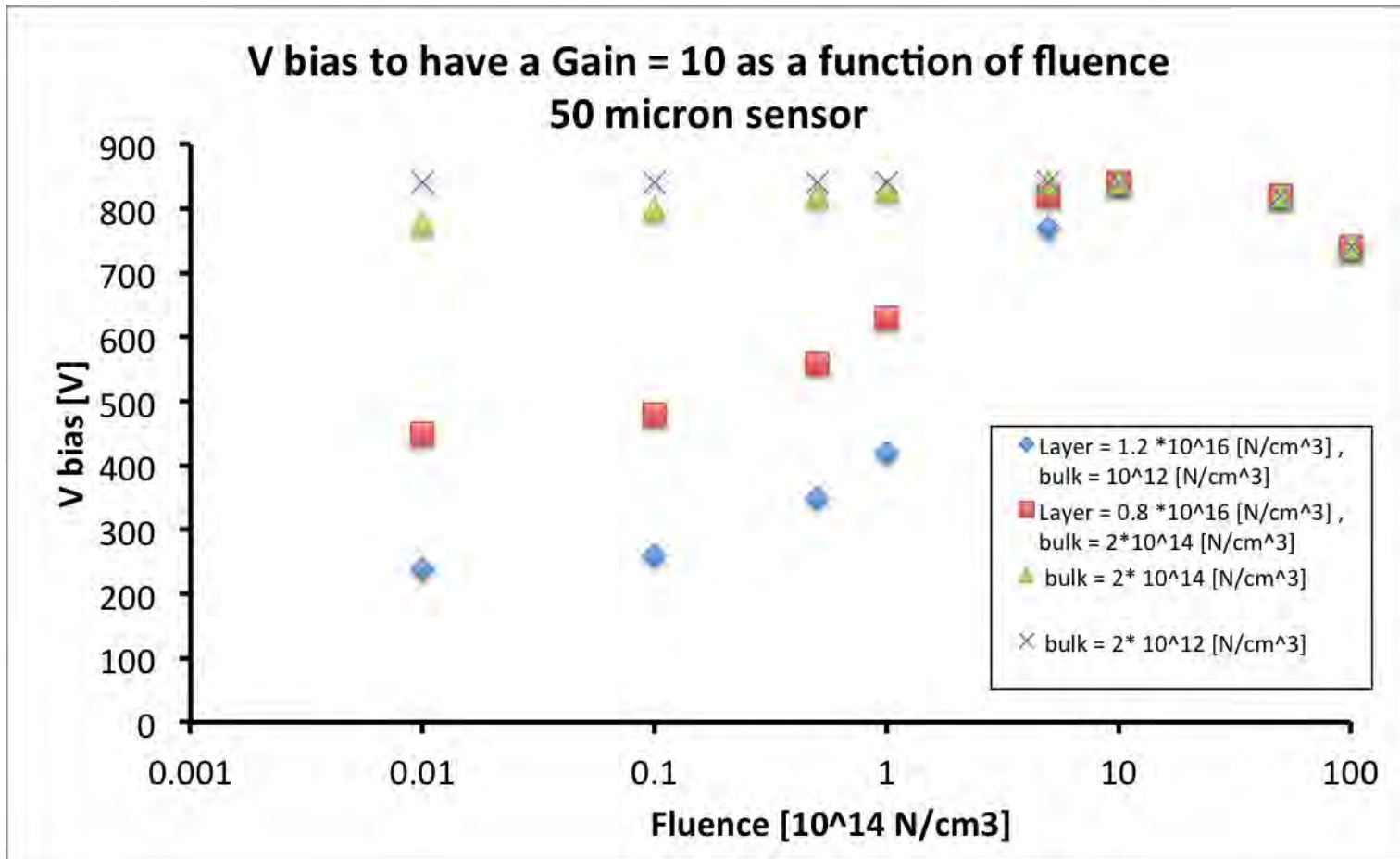
Good timing resolution requires a collected charge of $\sim 50\text{ke-}$

The collected charge can be held constant with increasing the bias voltage when the multiplication layer decreases.



E-field in LGAD bulk adds to the “gain field”

Internal gain reduces operating voltages required to reach multiplication



Model courtesy Nicolo Cartiglia

Preliminary, subject to refinement of acceptor removal model.



Conclusions

- Low-Gain Avalanche Detectors (LGAD) with gain of ~ 10 promise to give very good timing resolution when they are made thin.
- We are achieving about 50 ps timing resolution in the laboratory with 75um thick LGAD using a ^{90}Sr source and a fast trigger counter.
- The gain layer in the detectors adds additional radiation sensitivity beyond the one for no-gain silicon detector
- There is a program in place to reduce the radiation sensitivity by using thin sensors,
changing the dopant and wafer type to reduce “acceptor removal”
devise an operational strategy to keep the collected charge constant



Contributors

A. Anker, J. Chen, V. Fadeyev, P. Freeman, Z. Galloway, B. Gruey, H. Grabas, L. Hibbard,
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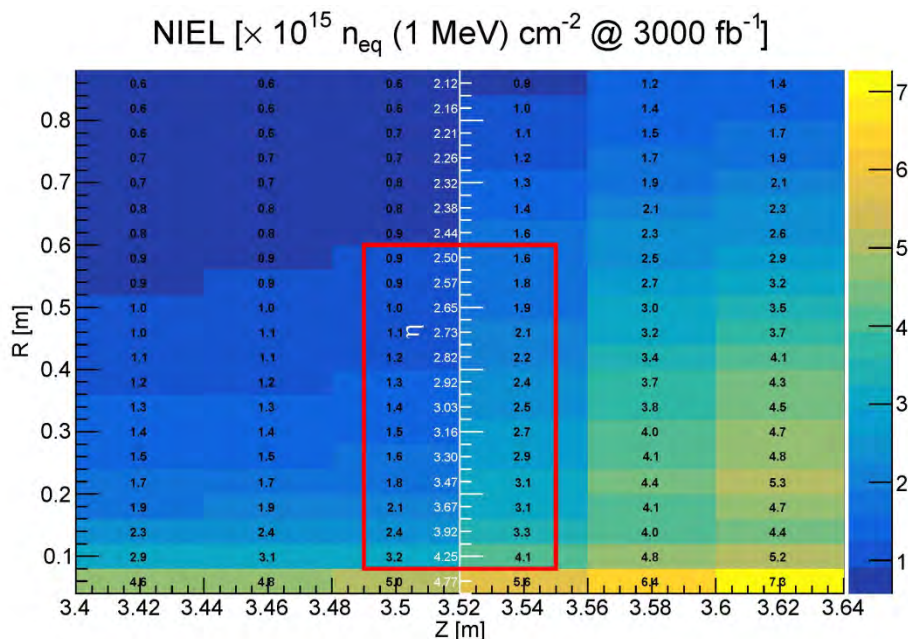
*Students in **bold***



R-Z dependence of Fluence @ HGTD

Data from F. Lanni: NIEL

based on M. Shupe's HGTD presentations

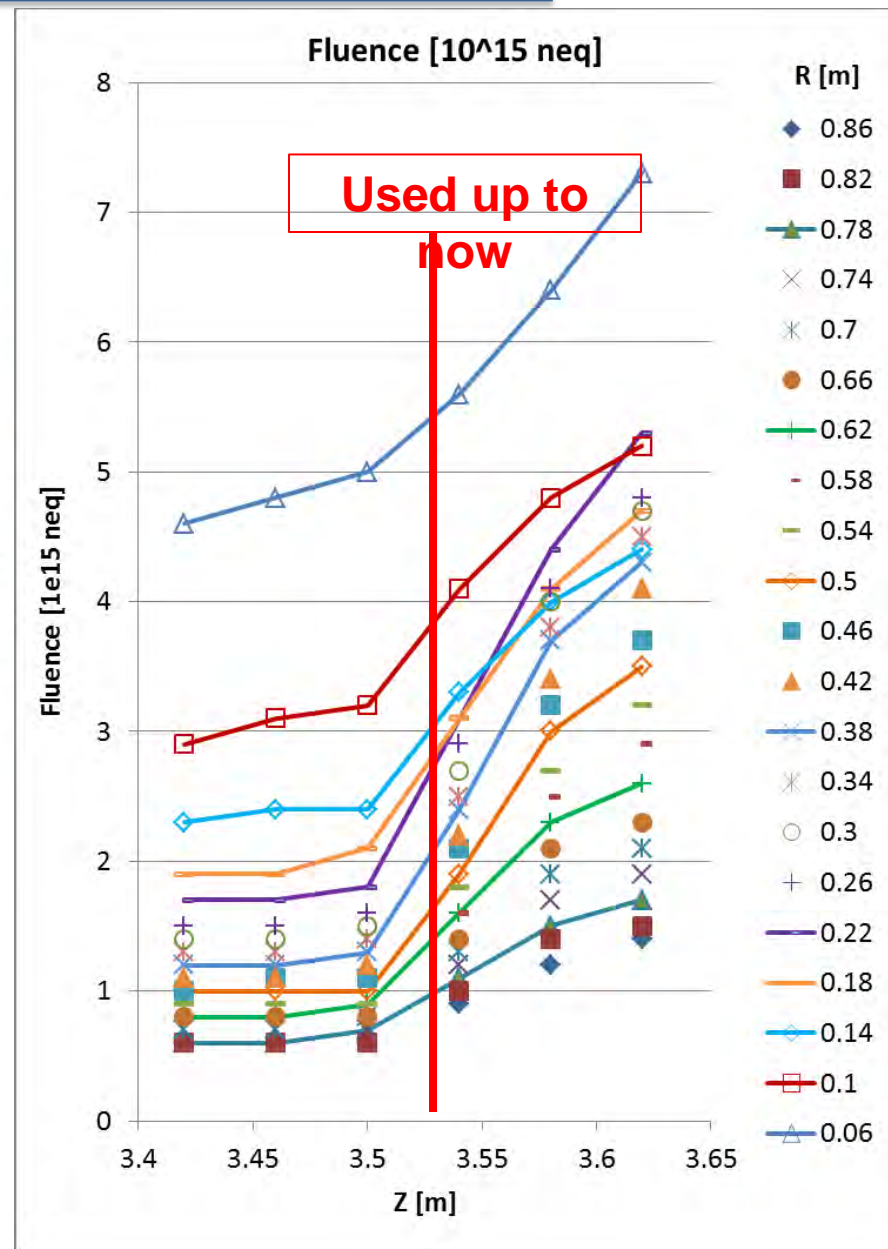


The R-Z plot shows a strong increase in the z-dependence of the fluence in the HGTD region.

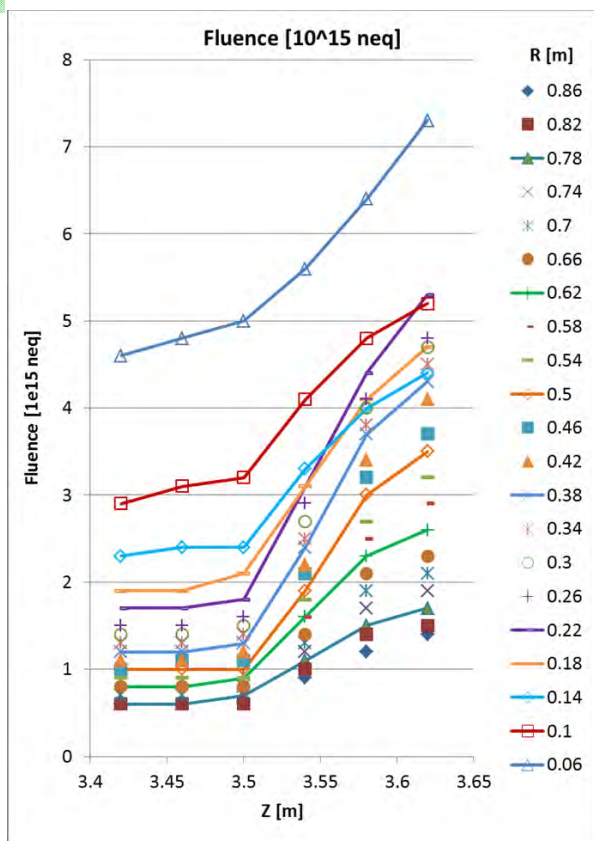
Presently use fluence values at $z = 3.53 \text{ cm}$.

At $z = 3.4$ fluence $\sim 10 - 20\%$ lower

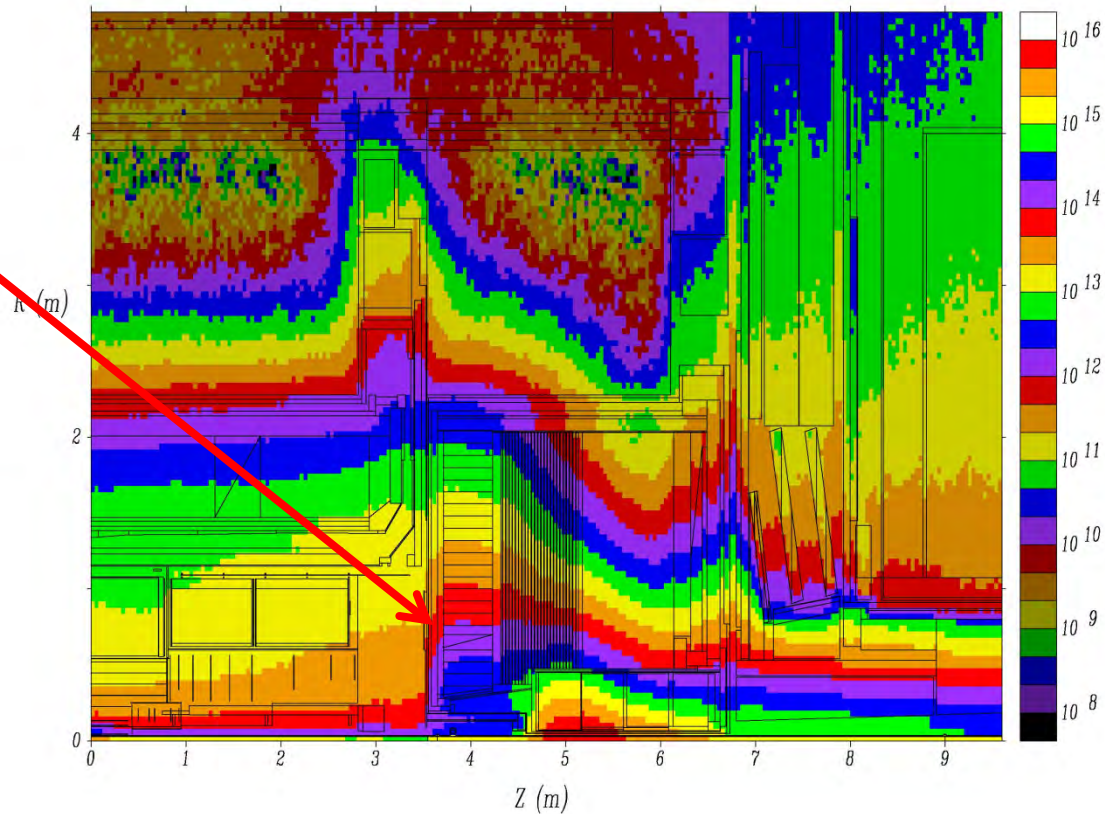
At $z = 3.6$ fluence $\sim 30\%$ higher



R-Z dependence of Fluence @ HGTD

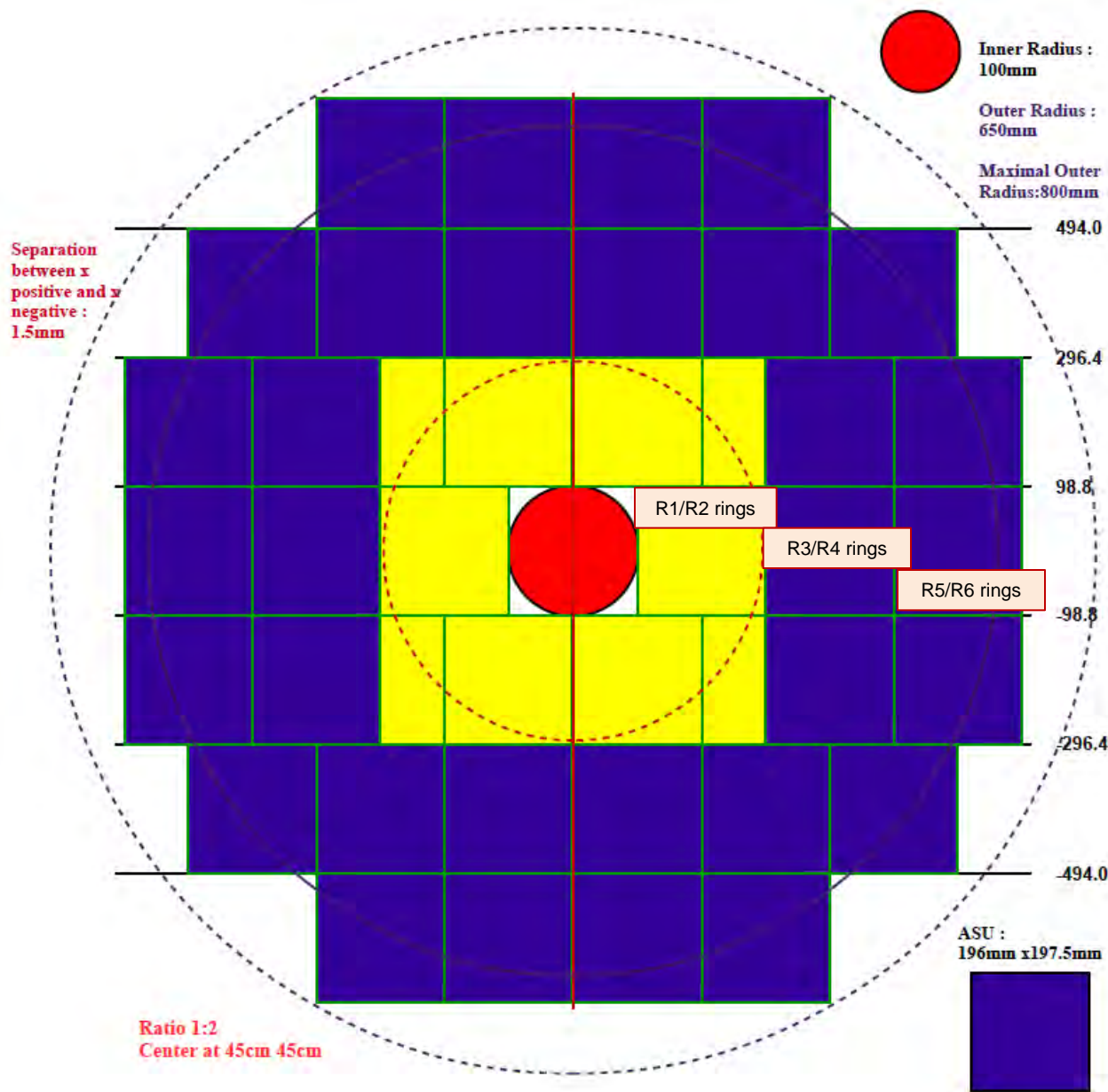


HGTD 2015 TD Ri9 Only 14 TeV 1744 EvtS - 1 MeV Neut Equiv/cm**2/Yr (NIEL)



The z-dependence in the HGTD region is part of a larger-scale trend in front of the FCAL.
Albedo?

HGTD at End Cap side/ End View from Simulation studies

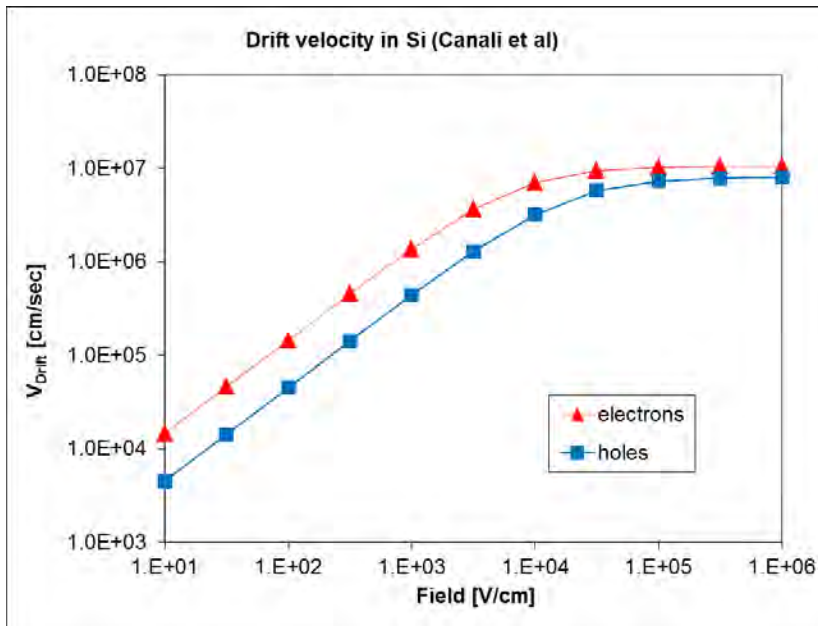


Basic Sensor unit:
 96.0x96.0mm² active
 (thickness=150
 micron)

Number of Sensors
 per Plane: 4x46=184
 (~16960cm² active)

Number of Sensors
 per HGTD-disk:
 4x184=736
 (~67830cm² active)

Charge Collection Time in Si Sensors



Drift velocity saturates for both electrons and holes!

-> need thin sensors or large over-depletion for fast charge collection

Collection time is close to minimum when
E-Field ≥ 20 kV/cm

For 300um Si
Collection time ~ 4 ns (h), ~ 3 ns (e)

For 50um Si
Collection time ~ 0.7 ns (h), ~ 0.5 ns (e)

